

PATENT  
0965-0413P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: YANAGIDA, Hisashi                      Conf.:  
Appl. No.: NEW    Group:  
Filed: August 29, 2003                              Examiner:  
For: ELECTROSTATIC CHUCK SUPPORT MECHANISM,  
SUPPORT STAND DEVICE AND PLASMA  
PROCESSING EQUIPMENT

PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

August 29, 2003

Sir:

The following preliminary amendments and remarks are respectfully submitted in connection with the above-identified application.

This reply includes:

Amendments to the Claims

Remarks